The interaction of titanium films with water vapour over a wide range of pressures and exposures

Kandasamy, K. and Surplice, N.A.

Phys. Dept., Univ. of Keele, Keele, United Kingdom

Abstract

The changes of work function phi and resistance R were studied when titanium films were exposed to water vapour at pressures p from UHV to 1.5 Torr and exposures q from 0-10⁴ Torr s. The work function was reduced by 0.8+or-0.2 eV at p approximately 10^{-3} Torr and q approximately 1 Torr s, then at p approximately 10^{-2} Torr and q approximately 10-100 Torr s it began to increase again. Finally when p was increased to 1.5 Torr and q to approximately 104 Torr s phi was 0.1 eV less than the original value of phi for the clean film. The resistance was increased monotonically by about 10%. Hydrogen was evolved as each dose of water vapour was added to the film, and some of it was re-absorbed by the film. Complementary studies were made of the effects of mixtures H₂ and O₂, and of the successive sorptions H₂O/O₂/Ti and O₂/H₂O/Ti. The data implied that the decrease in phi was mainly due to the effects of the adspecies OH and H₂O and the subsequent increase in phi may have been due to a mixed layer of oxides and hydroxide forming on the metal surface.